

PATENT
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Li, et al.

Serial No.: 10/645,675

Confirmation No.: 8295

Filed: August 20, 2003

**For: Methods of Reducing
Plasma-Induced Damage
for Advanced Plasma CVD
Dielectrics**

Group Art Unit: 2812

Examiner: Tuan H. Nguyen

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I hereby certify that this correspondence and the documents referred to as attached therein are being facsimile transmitted to the U.S. Patent and Trademark Office to the fax number indicated by the Examiner, namely, fax number 703-872-9306 to the attention of the named Examiner, on the date below.

2/23/05
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Kirsten A. Zuck
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AMENDMENT AFTER ALLOWANCE

Following mailing of a Notice of Allowance on January 27, 2005, Applicants request entry of the following amendments. **Amendments to the Specification** are shown beginning page 2 of this paper. **Amendments to the Claims** begin on page 3 of this paper. **Remarks** begin on page 8 of this paper.

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TN 5/10/05